



503.36911X00

11/c
B. H.
7-11-01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): T. ONO, et al

RECEIVED

Serial No.: 09/249,292

JUL 10 2001

Filed: February 12, 1999

TC 1700

For: METHOD AND APPARATUS FOR TREATING SURFACE OF SEMICONDUCTOR

Group: 1746

Examiner: A. Alanko

AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

July 5, 2001

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application in response to the Office Action dated January 4, 2001.

IN THE CLAIMS:

Please add the following new claims:

--24. A method according to claim 1, further comprising the step of etching the surface of the sample so as to obtain a feature size no greater than 1 μ m at at least a portion of a surface of the sample.

25. A method according to claim 1, further comprising the step of etching the surface of the sample so as to obtain